

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al.                      Art Unit : Unknown  
Serial No. : New Application                              Examiner : Unknown  
Filed : October 29, 2003  
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Prior to examination, please amend the application as indicated on the following pages.

**Amendments to the Specification** begin at page 2 of this paper.

**Remarks/Arguments** begin on page 3 of this paper.